



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Zhang et al.

Serial No.: 09/722,400

Filed: November 27, 2000

For: POLYIMIDE AS A MASK IN VAPOR

HYDROGEN FLUORIDE ETCHING

Confirmation No.: 5784

Examiner: C. Young

Group Art Unit: 1756

Attorney Docket No.: 2269-7144.2US

(95-0813.02/US)

CERTIFICATE OF MAILING

I hereby certify that this correspondence along with any attachments referred to or identified as being attached or enclosed is being deposited with the United States Postal Service as First Class Mail on the date of deposit shown below with sufficient postage and in an envelope addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

January 3, 2006

Leta M. Howard Name (Type/Print)

<u>AMENDMENT</u>

Mail Stop Amendment Commissioner for Patents PO Box 1450 Alexandria, VA 22313-1450

Sir:

The following amendments and remarks are filed in response to the Examiner's remarks in the Office Action mailed October 3, 2005 ("Action"), the three-month shortened statutory period for response to which expires on January 3, 2006.

Amendments to the Specification begin on page 3 of this paper.

Amendments to the Abstract appear on page 4 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 5 of this paper.

Amendments to the Drawings begin on page 9 of this paper and includes attached replacement sheets.

Remarks begin on page 10 of this paper.

An **Appendix** including formal drawing figures is attached following page 13 of this paper.